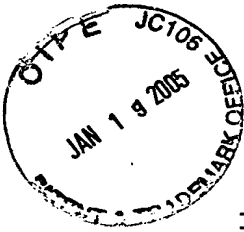


IFW



PATENT
8008-1047

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Michinobu TANIOKA et al.

Conf. 6821

Application No. 10/695,388

Group 2829

Filed October 29, 2003

Examiner Minh Nhut Tang

SEMICONDUCTOR DEVICE INSPECTION
APPARATUS AND INSPECTION METHOD

AMENDMENT

MS AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 19, 2005

Sir:

In response to the Office Action mailed October 19, 2004, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 9 of this paper.

Amendments to the Drawings begin on page 18 of this paper and include an attached replacement sheet.

Remarks begin on page 19 of this paper.

An **Appendix** is attached following the signature page of this paper.

AMENDMENTS TO THE DRAWINGS:

A replacement drawing is submitted for Figure 1 changing reference character 22 to reference character 25.

Attachment: Replacement Sheet